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		First Named Inventor	Ulrich Speh, et al
		Group Art Unit	
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U. S. PATENT DOCUMENTS							
Examiner Initials	Cite No.	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date
JWS	5	5,503,171	04/02/1996	Yokomizo et al			12/22/1993
	6	5,203,798	04/20/1993	Watanabe et al			06/24/1991
	8	5,836,325	11/17/1998	Akanuma et al			09/16/1996

FOREIGN PATENT DOCUMENTS							
Examiner Initials	Cite No.	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation Yes No
JWS	1	EP0817246A1	07 Jan 1998	Europe			X
	11	DE19616400	06 Nov 1997	Germany			X

OTHER PRIOR ART B NON PATENT LITERATURE DOCUMENTS		
Examiner Initials	Cite No.	
JWS	2	JP 5-291223, Water Cleaning Apparatus
	3	JP 06005577, Substrate Cleaning Device
	4	JP 03020031, Ultrasonic Cleaning Device
	7	JP 6-73598, Method fro Producing Semi-conductor and Device Thereof
	9	JP 6-244164 (1), Ultrasonic Cleaning Device
	10	JP 10308376 (A) Cleaning of Wafer and Wafer Cleaning Device
	12	JP 62-279640, Wafer Washing Apparatus
	13	JP 5-166793 (A) Dipping Type Substrate Treatment Apparatus
	14	JP 10163158 A Cleaning Apparatus for Sheetlike Body
	15	JP 10163164 A Substrate Treatment Method and Substrate Treatment Apparatus
	16	JP 07066100 A Air Knife and Processor Using the Same
	17	JP 4-10416 (A) Method and Apparatus for Drying Substrate
	18	JP 06326067 A Substrate Treatment Apparatus

Examiner	<i>JWS</i>	Date	4/19/04
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